

10/087060
02/27/02
APPL. NO.
1145

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM	FILING DATE	CLASS	SUBCLASS	GAU	EXAMINER
10087060	02/27/2002	250		2878	✓ S. E. J.

**APPLICANTS: Saito Etsuro; Motomura Yuuichi;

**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:

JAPAN P2000-207311 07/07/2000

PCT/JP01/05921 07/06/2001

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiners initials		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no	21778.05600
TITLE : Quantity-of-light unevenness inspection apparatus, and quantity-of-light unevenness inspection method			
U.S. DEPT. OF COMM./PAT. & TM-PTO-438L (Rev. 12-94)			

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg.	Print Fig.
TERMINAL DISCLAIMER		Primary Examiner		
		Application Examiner		
PREPARED FOR ISSUE		WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.		

FILED WITH:

DISK (CRF)

CD-ROM

(Attached in pocket on right inside flap)